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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 1632

Norio KIMURA et al.

Docket No. 2001-0660A

Serial No. 09/864,208

Group Art Unit 1763

Filed May 25, 2001

Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS AND SUBSTRATE POLISHING METHOD

MAIL STOP: AF

RESPONSE UNDER 37. CFR 1.116

EXPEDITED PROCEDURE

EXAMINING GROUP 1763

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of May 16, 2005, kindly amend the above-referenced U.S. patent application as follows: